



Design and characterization of a monolithic diamond ΔE -E telescope for particle identification

doctoral seminar

Alexandre PORTIER

PhD director: **Marie-Laure Gallin-Martel (LPSC)**

PhD co-director: **Julien Pernot (Institut Néel)**

The 15 / 03 / 2021

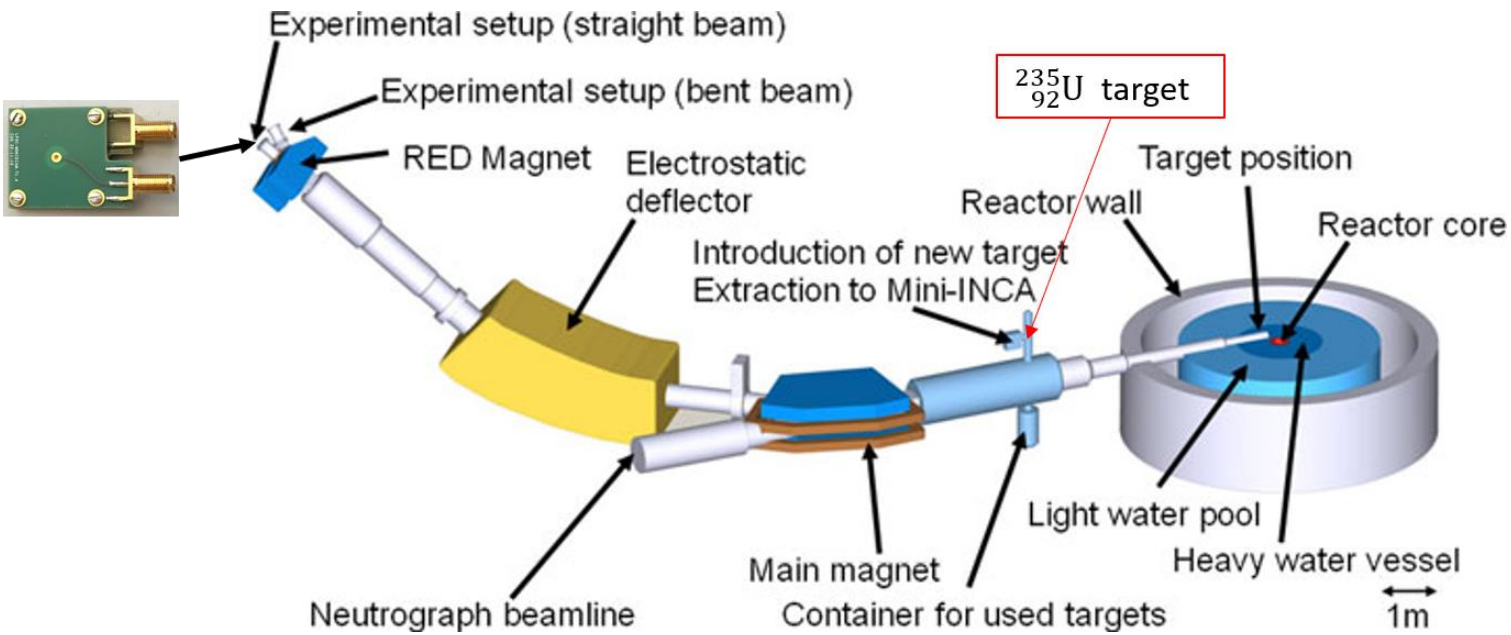
International collaboration: Japan-France collaboration (test of Japanese pn junction) ; experiments at ILL (Lohengrin and FIPPS)

Project DIATEL (IDEX UGA) hold by Denis Dauvergne + **Project DIAMTECH (IN2P3-CNRS)** hold by Marie-Laure Gallin-Martel

PRC JSPS – CNRS TYL IN2P3

PhD thesis motivations

LOHENGRIN experiment at ILL



LOHENGRIN spectrometer at the Laue-Langevin Institut Grenoble.

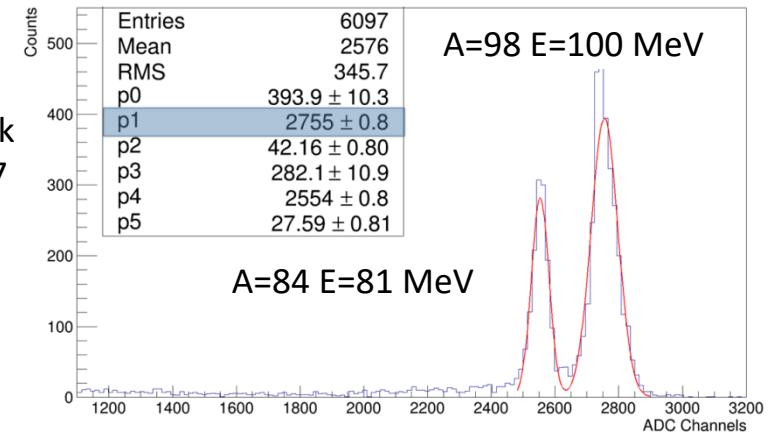
- **A magnetic field** deflects vertically the FF according to their $\frac{E}{q}$
- **An electric field** deflects horizontally the FF according to their $\frac{A}{q}$

PhD thesis motivations

LOHENGRIN experiment at ILL

=> one should expect that the FF98 peak at the energy of 100 MeV is at ADC = 5527

BUT : observed at the channel 2755 !!!!

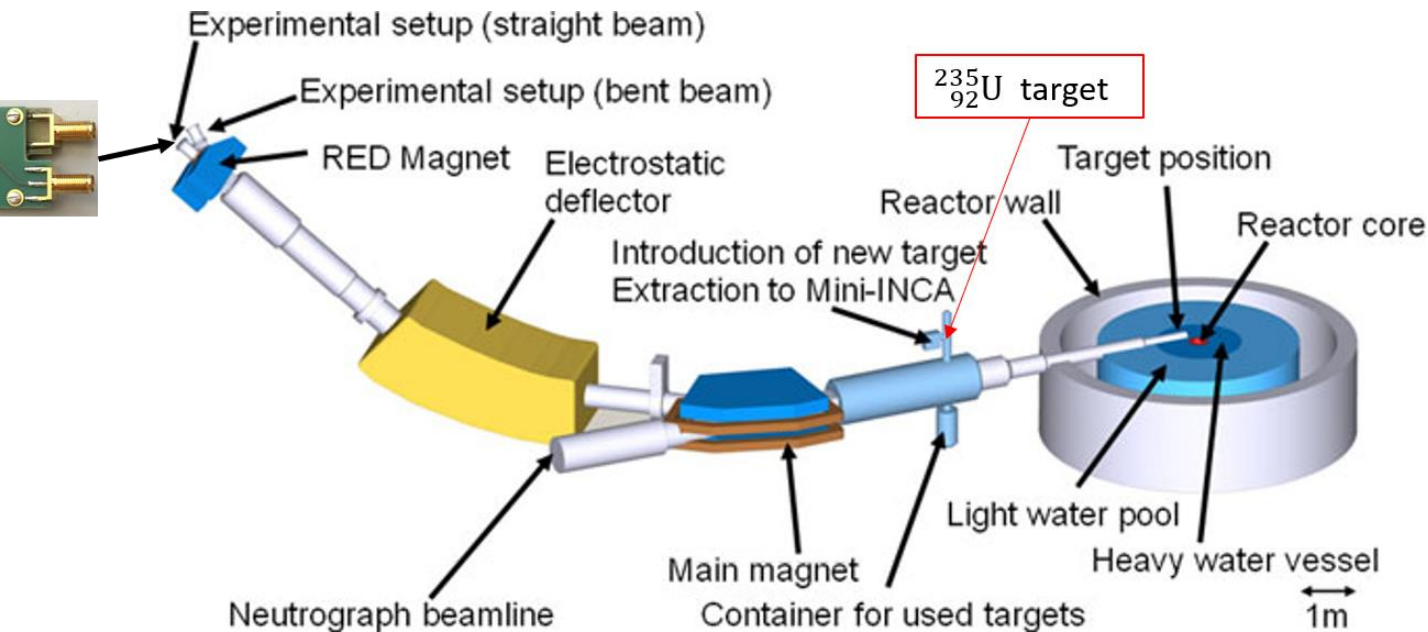
The Pulse Height Defect (PHD) :

$$\Delta E = E_k - E_{DD}$$

E_k : The kinetic energy of an incident ion.

E_{DD} : The energy derived from the measured electric signal.

50 % of the deposited energy is not reconstructed: Pulse Height defect !

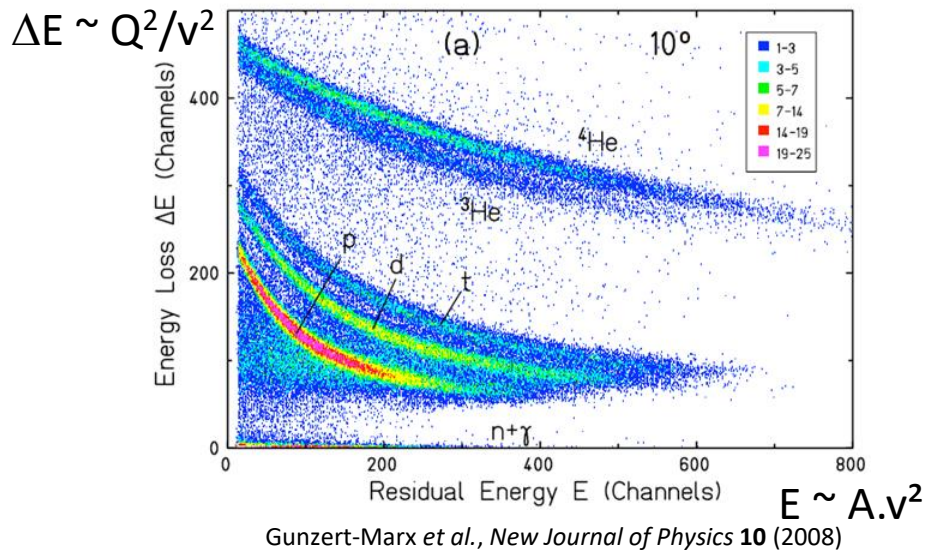
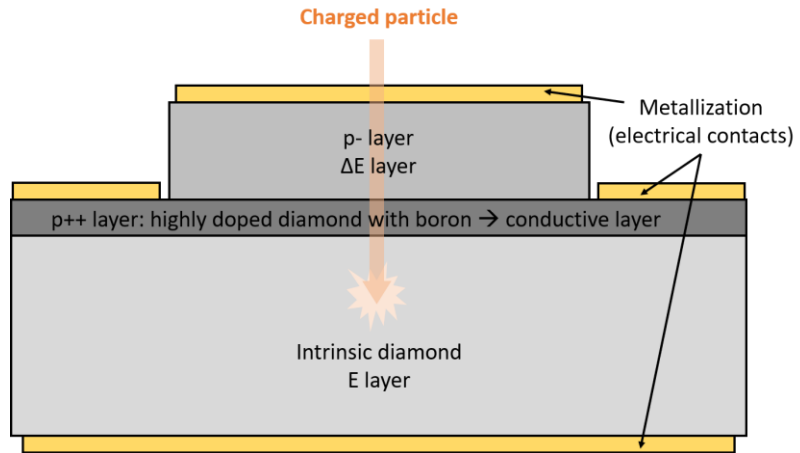


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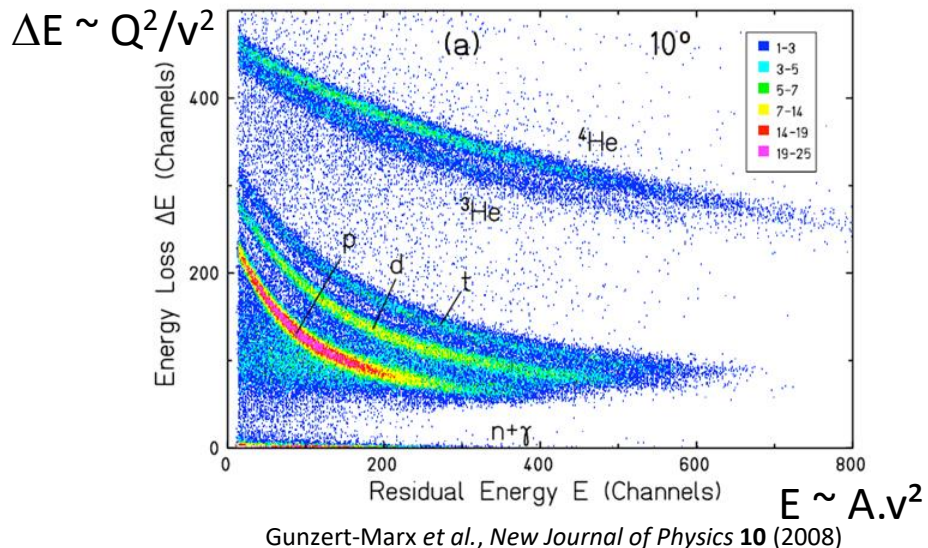
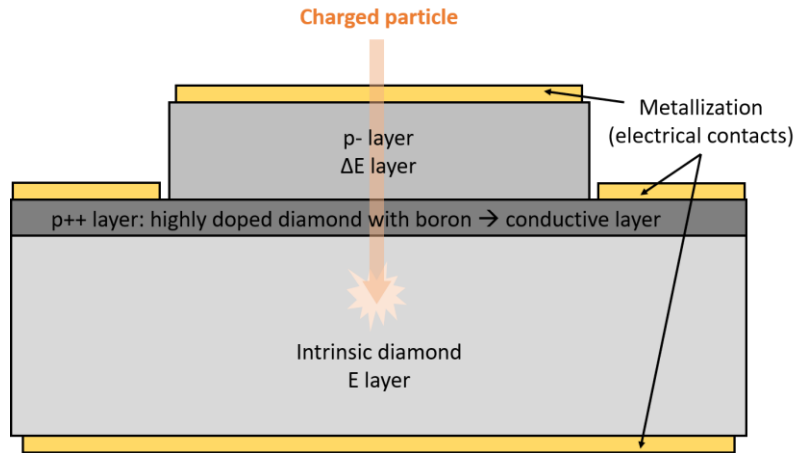
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PhD thesis main goals

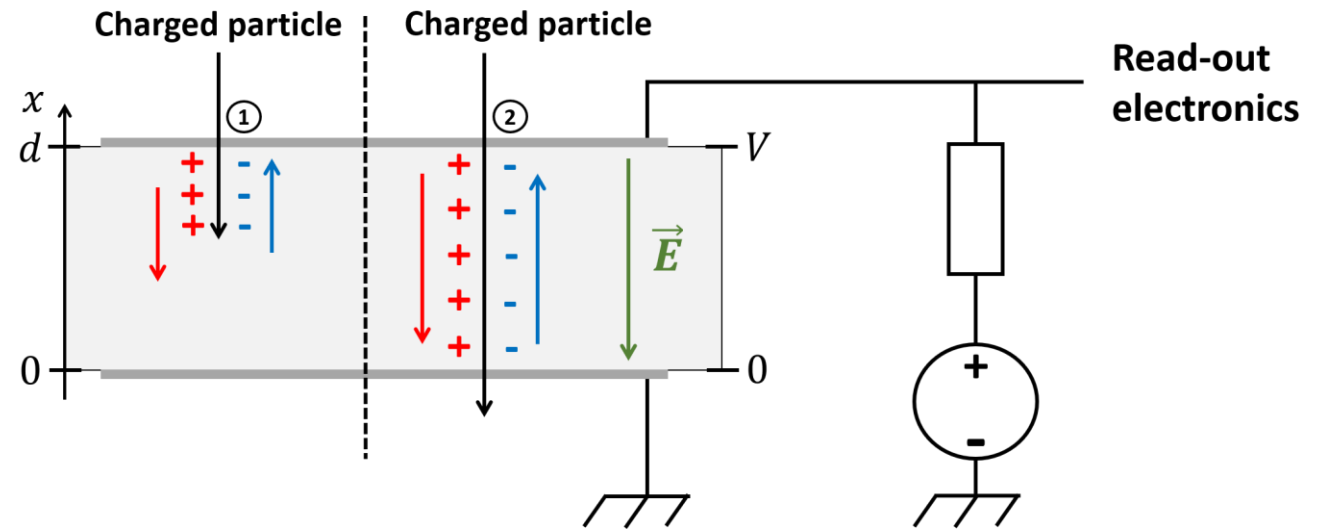
ΔE -E detector



PhD thesis main goals

 ΔE -E detector

Solid ionization chamber

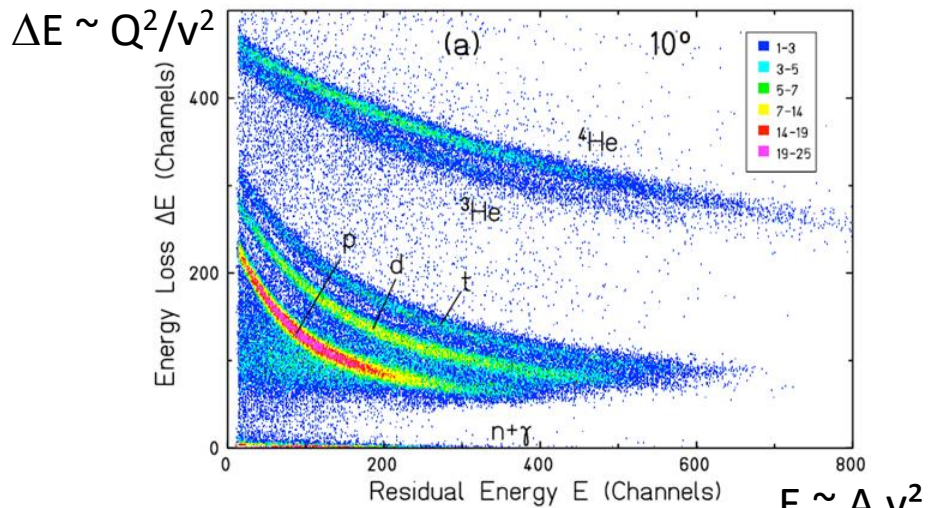
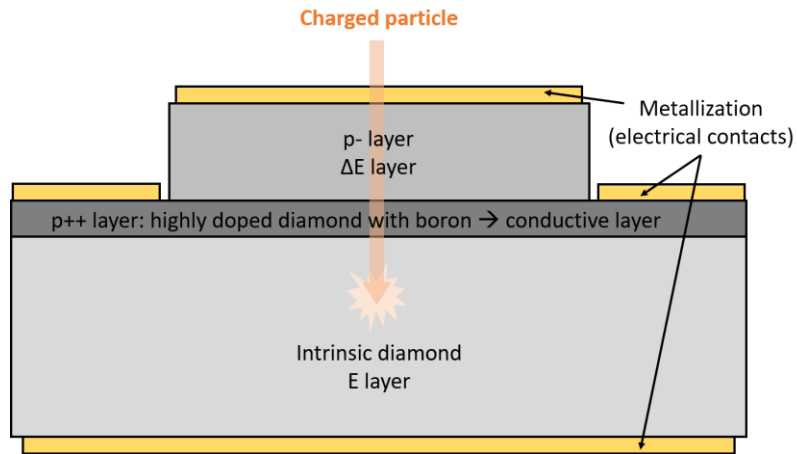
Charge particle in the medium:

- Ionization: electron – hole pairs creation
- Electric field \rightarrow charge carriers drift

Two different situations:

1. Particles that stop in the detector
2. Particles that pass through the detector

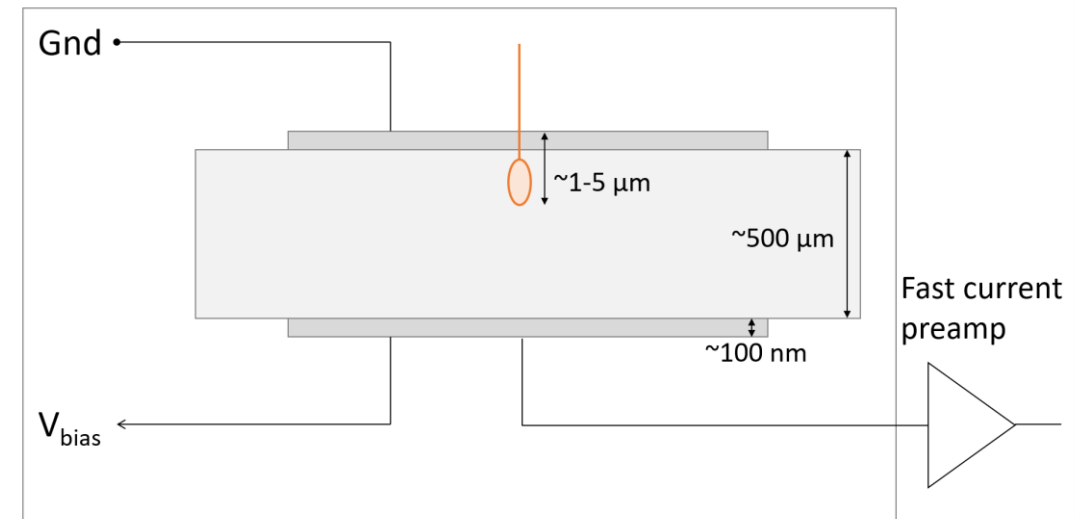
PhD thesis main goals

 ΔE -E detector

Gunzert-Marx et al., *New Journal of Physics* 10 (2008)

ToF – eBIC setup development

Time of Flight – electron Beam Induced Current



Study low range particles which stop in the detector

Beam \rightarrow allow to control the charge injection
Not the case for radioactive sources

Diamond properties

Physical properties compared at 300 K

	Diamond	Silicon	SiC
Undoped material resistivity ($\Omega \cdot \text{cm}$)	$> 10^{13}$	$2.3 \cdot 10^5$	$> 10^5$
Bandgap (eV)	5.5	1.1	3.26
Pair creation energy e^-/h^+ (eV)	13.1	3.6	7.8
Displacement energy (eV)	43	25	20 - 35
Carrier mobility ($\text{cm}^2 \cdot \text{V}^{-1} \cdot \text{s}^{-1}$)	> 2000	800 – 1400	115 - 1000
Thermal conductivity ($\text{W} \cdot \text{cm}^{-1} \cdot \text{K}^{-1}$)	20	1.5	1.2

Diamond as a detector :

- ✓ Very low leakage current
- ✓ Low noise
- ✓ Good radiation hardness
- ✓ Very fast
- ✓ Work at room temperature



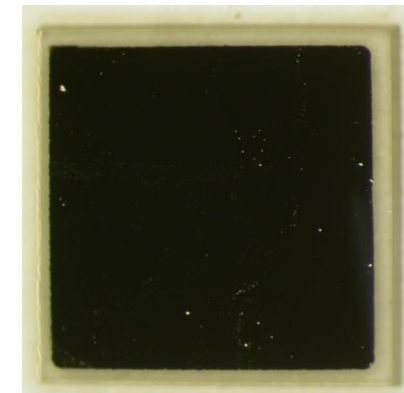
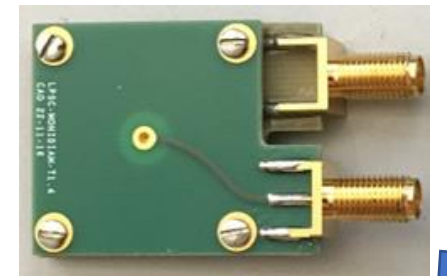
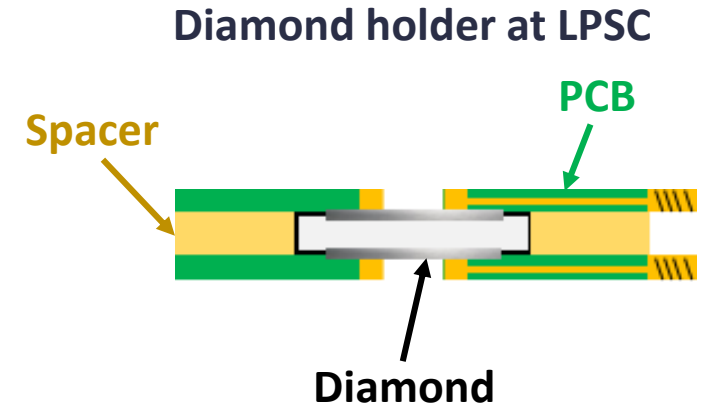
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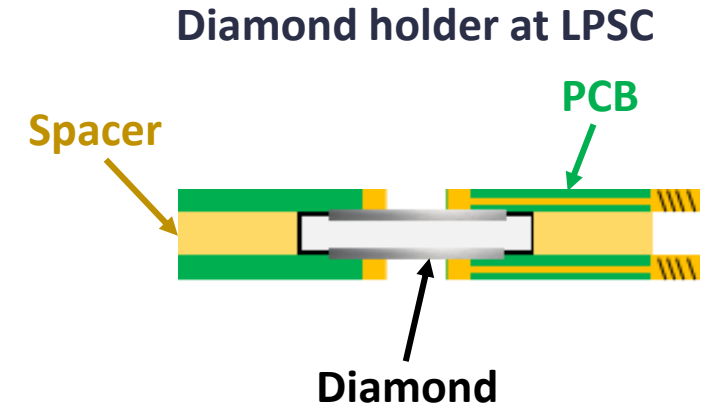
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Read out electronic and acquisition



Large bandwidth
current preamplifier
Gain > 40 dB
Bandwidth 2 GHz

Fast numerical
oscilloscope



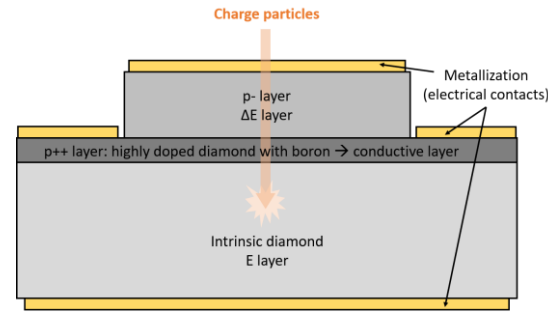
Outlines

1. ΔE -E detector : from simulation to first samples
 - SRIM Simulations & first design
 - First sample processing steps
2. Electron Beam Induced Current (eBIC) experiments at Néel
 - Set up of the experiment
 - Time of flight studies
 - Diamond properties study at different temperatures
 - Detector mappings

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SRIM simulations – requirements

Goals:

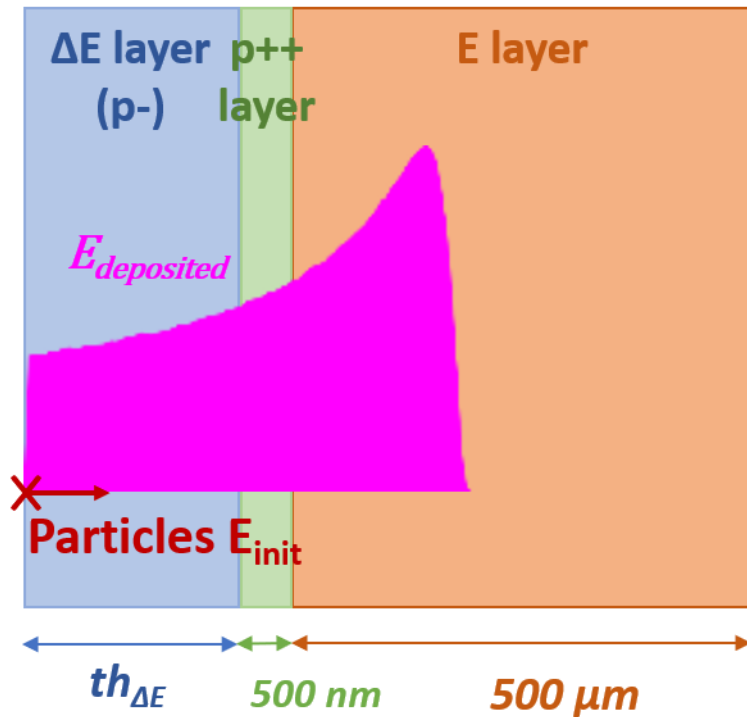
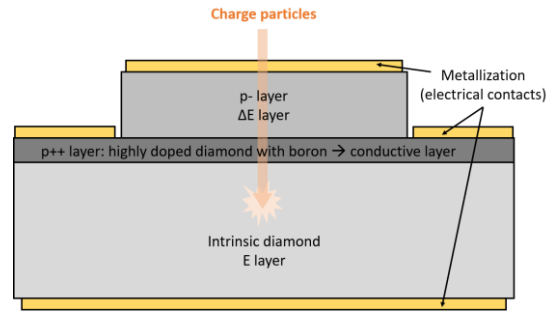
Simulate the energy deposition in the ΔE -E detector for different ions, ion energies and detector architectures.

Determine the thickness of the ΔE (p-) layer of the first sample

Layers	Parameters	Consideration & criteria	Requirements	Growth method
p- layer	Thickness	<ul style="list-style-type: none"> Energy deposition need to be measurable Resistivity and leakage current 	$(1 \text{ MeV} < \Delta E < E_{\text{init}}/2)$ $I_{\text{leak}} < 1 \text{ nA}$	MPCVD Microwave Plasma enhanced Chemical Vapor Deposition
	Doping	<ul style="list-style-type: none"> Non intentionally doped (Avoid defaults) 	As low as possible	
	Contact	<ul style="list-style-type: none"> Resistivity and leakage current 	$I_{\text{leak}} < 1 \text{ nA}$	
p++ layer	Thickness	<ul style="list-style-type: none"> Dead area of detection Growth layer feasibility 	thinnest as possible $> 200 \text{ nm} \rightarrow 500 \text{ nm}$	DiamFab
	Doping	<ul style="list-style-type: none"> Could be considered as a conductor 	$[B] > 10^{20} \text{ cm}^{-3}$	
Substrate	Thickness	<ul style="list-style-type: none"> Enough thick to stop the particle 	$\sim 550 \mu\text{m}$	E6 scCVD
	Doping	<ul style="list-style-type: none"> Non intentionally doped (Avoid defaults) 	As low as possible	

SRIM simulations – explanations

SRIM simulations explanation scheme



Goal : dimensioning the p- layer of the detector

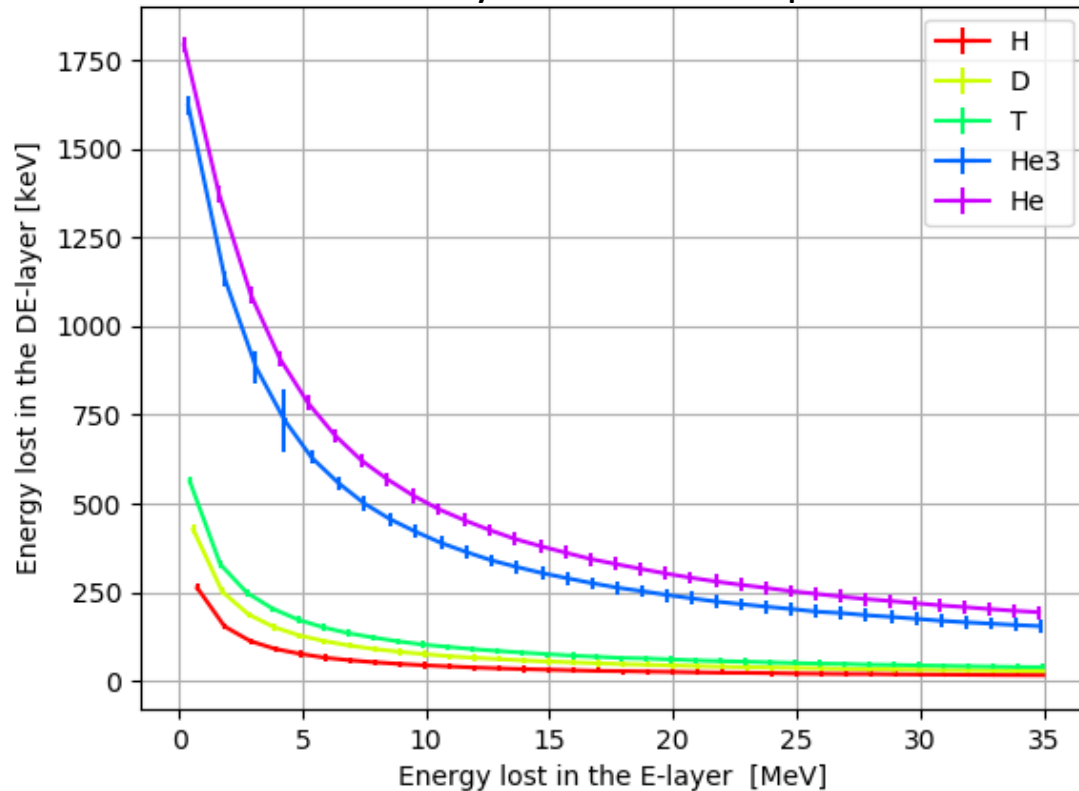
Simulation details :

- ❖ 1 ion (H, D, T, ^3He , ^4He , FF)
- ❖ Different ion initial energies (for ^4He : [1; 10] MeV)
- ❖ Different ΔE stage thickness $th_{\Delta E}$ [0.1, 10] μm

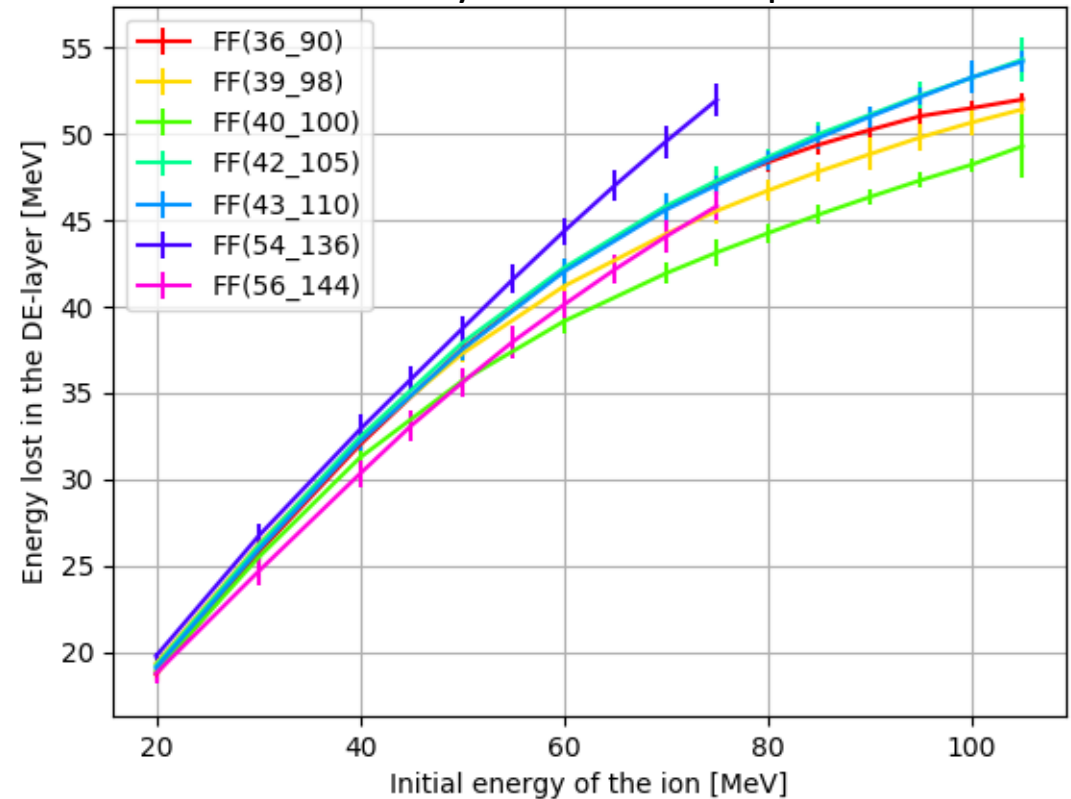
→ Graph $\Delta E \pm \sigma_{\Delta E}$ vs E_{init}

SRIM simulations – Results

SRIM simulations for light ions

 ΔE layer thickness: 3 μm 

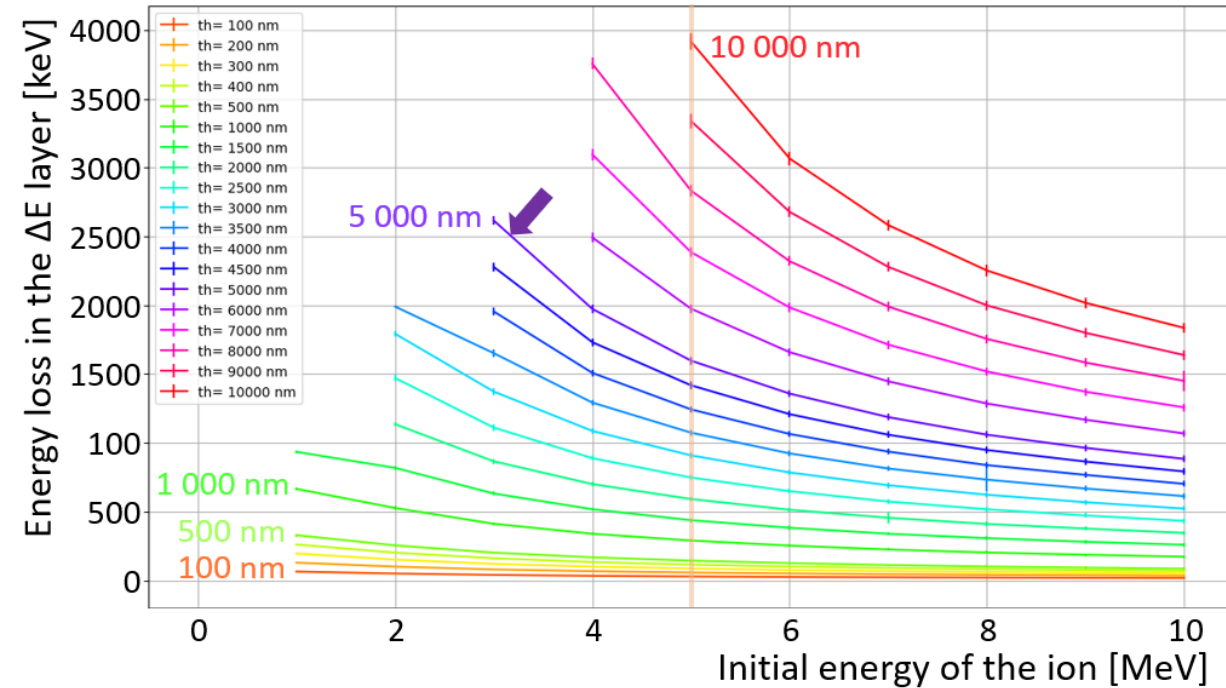
SRIM simulations for heavy ions

 ΔE layer thickness: 3 μm 

Observations : the mass ordering is respected for the light isotopes but not for the heaviest ones. **Discussion with Ulli Koester** \rightarrow difficult to do simulation using FF (Fission Fragments)

1st design based on the light ion simulations \rightarrow in particular: 5 MeV alpha particles

From simulations to first sample

SRIM simulations for α particles

Requirements: (For $E_{\text{init}} = 5\text{MeV}$)

Energy deposited:

$$E_{\Delta E} > 1 \text{ MeV}$$

$$E_{\Delta E} > E_{\text{init}}/2$$

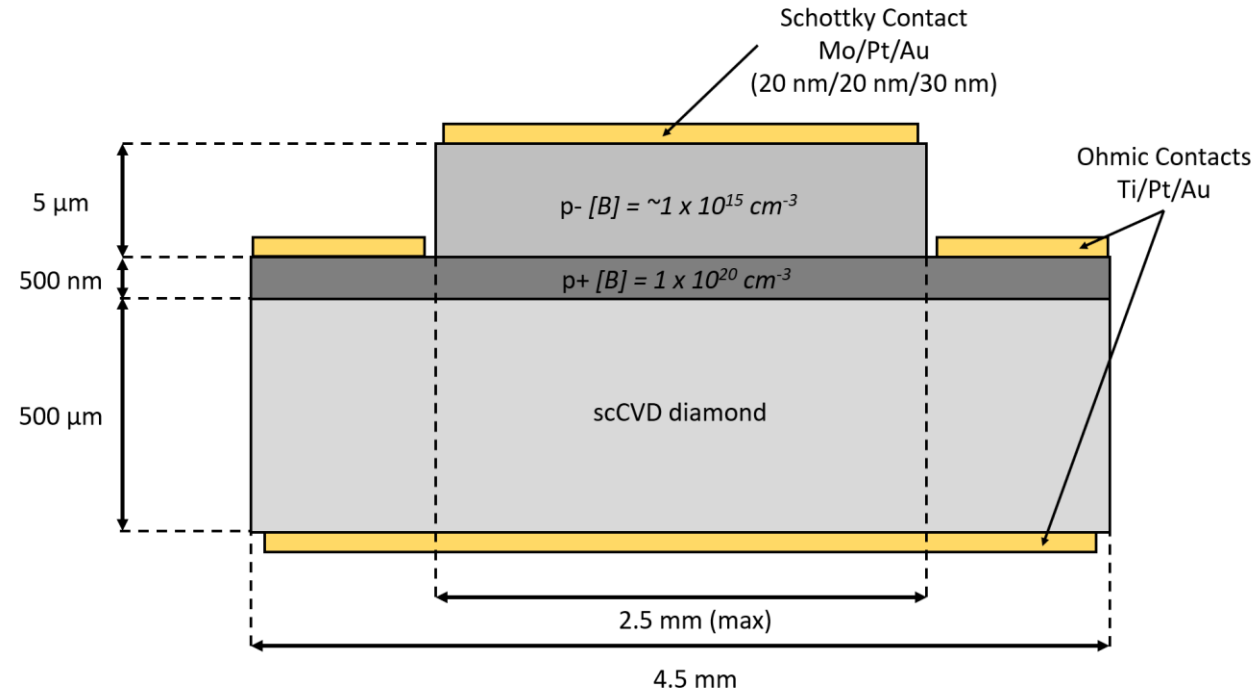
Leakage current:

$$I_{\text{leak}} < 1 \text{ nA}$$

Solution chosen:

Thickness: $5 \mu\text{m}$
Schottky Contact

First simple design scheme



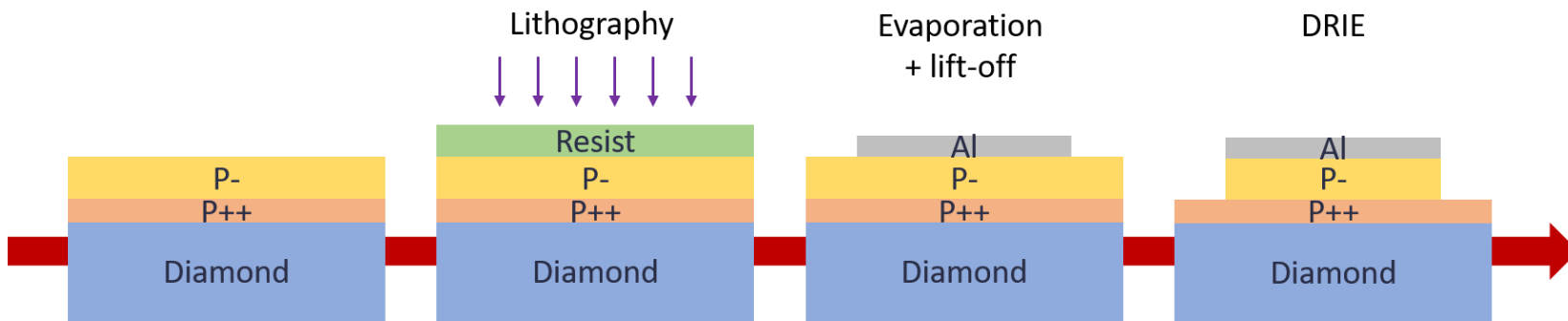
Alpha particle range
in diamond : $11.8 \mu\text{m}$

The start-up DiamFab is in charge of
the epitaxial growth.



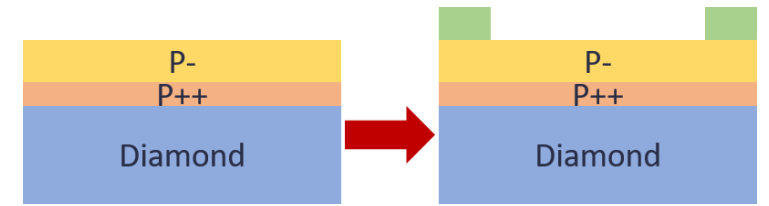
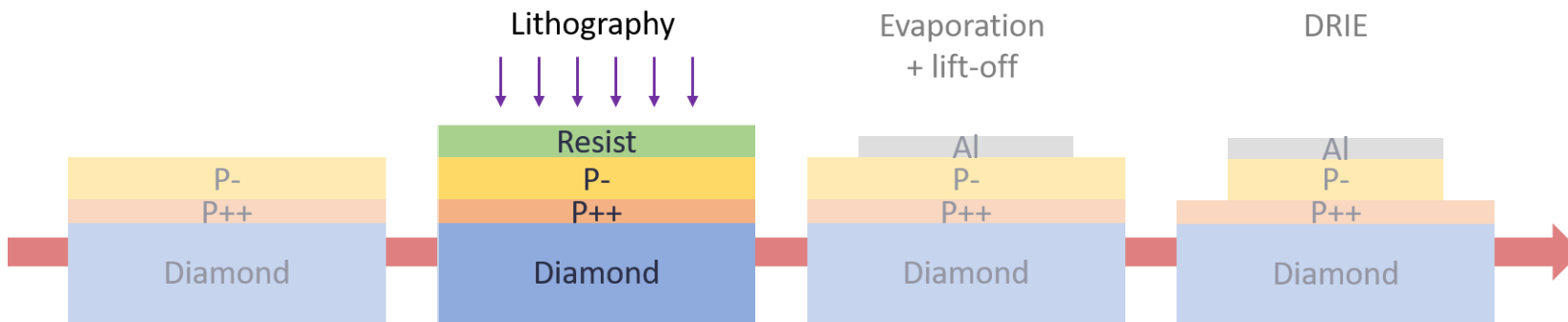
Etching process

Etching process



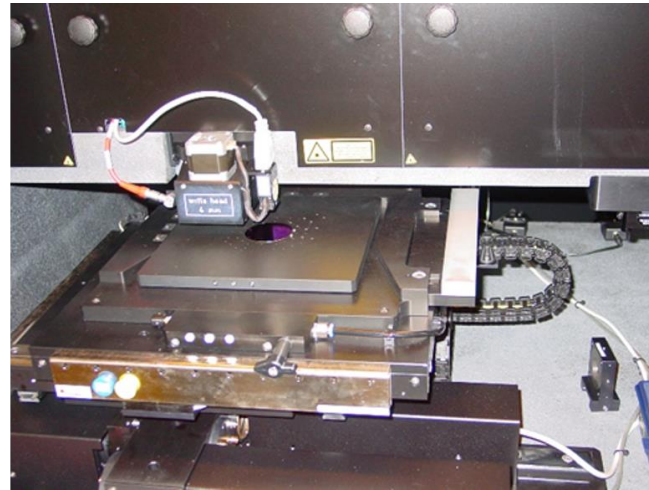
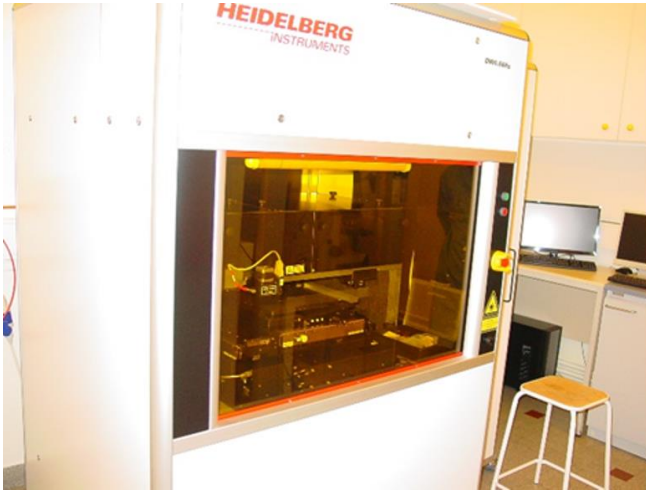
Etching process – lithography

Etching process



1

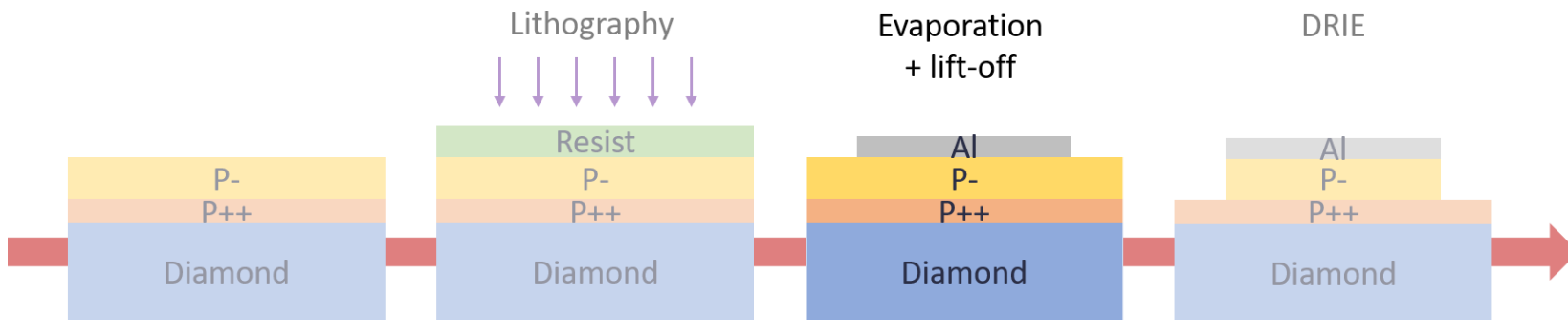
Mask conception on Klayout
Resist deposition
Lithography
Insulated resist lift-off



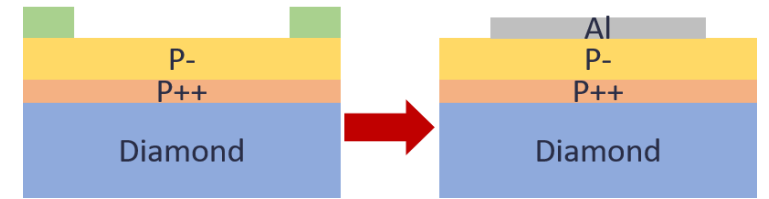
Lithography device at NanoFab clean room
NanoFab is a platform of Institut Néel

Etching process – Al evaporation

Etching process



Plassys: metal deposition device at NanoFab
 NanoFab is a platform of Institut Néel

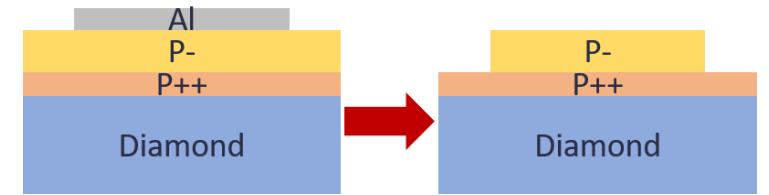
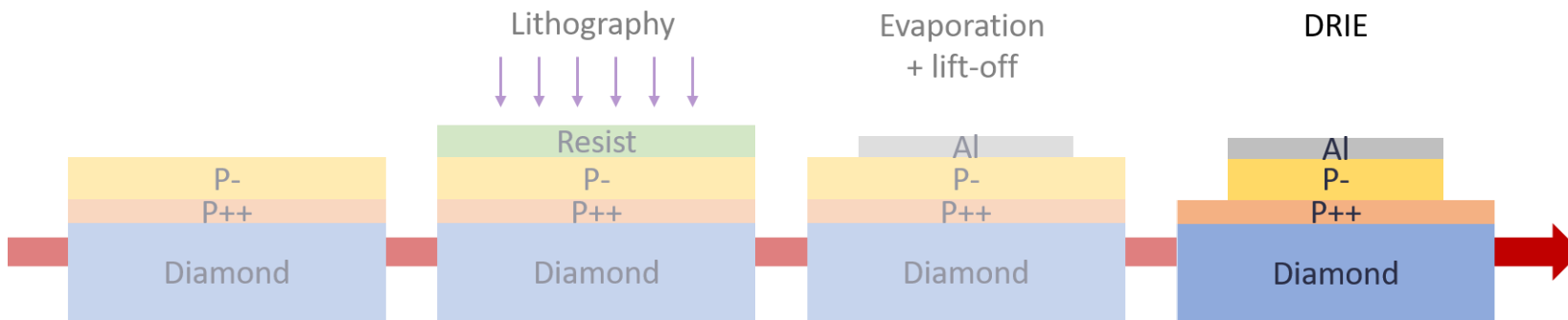


1 Mask conception on Klayout
 Resist deposition
 Lithography
 Insulated resist lift-off

2 Aluminium evaporation
 Lift-off

Etching process – DRIE

Etching process



1 Mask conception on Klayout
Resist deposition
Lithography
Insulated resist lift-off

2 Aluminium evaporation
Lift-off

3 Deep etching at PTA
Aluminium lift-off

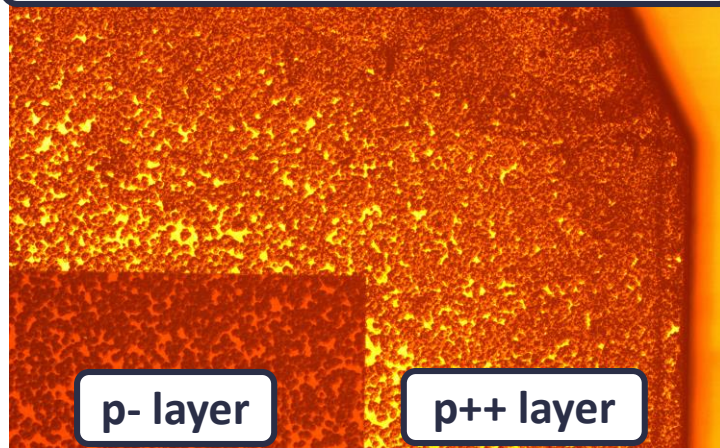


Aqua Regia for aluminium lift-off
(HCl + HNO₃)

PTA: Plateforme Technologique Amont
DRIE: Deep Reactive-Ion Etching

First sample – etching checking

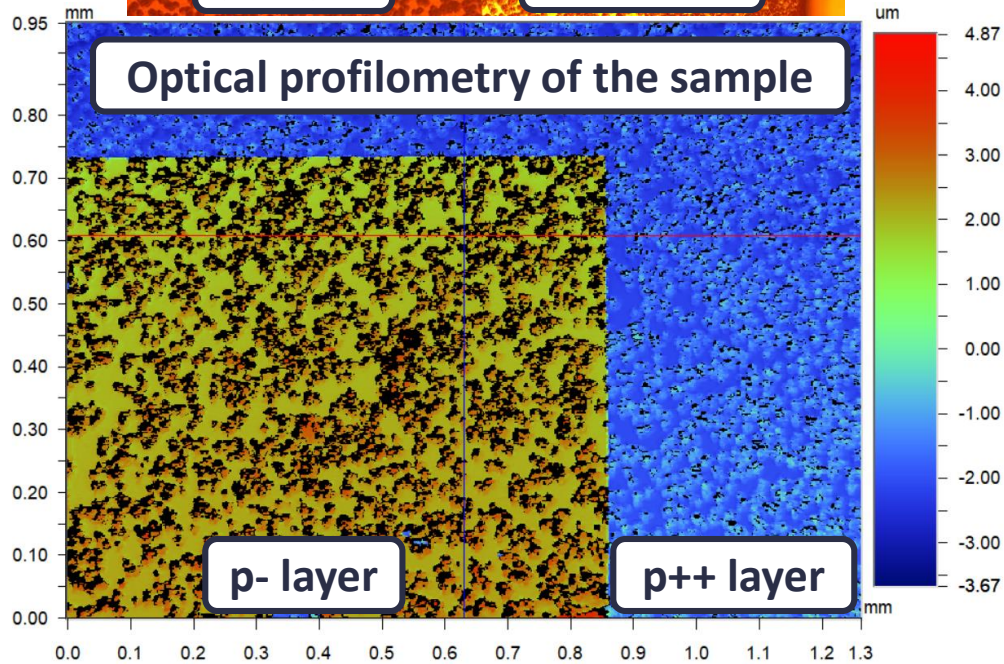
Microscope picture of the sample



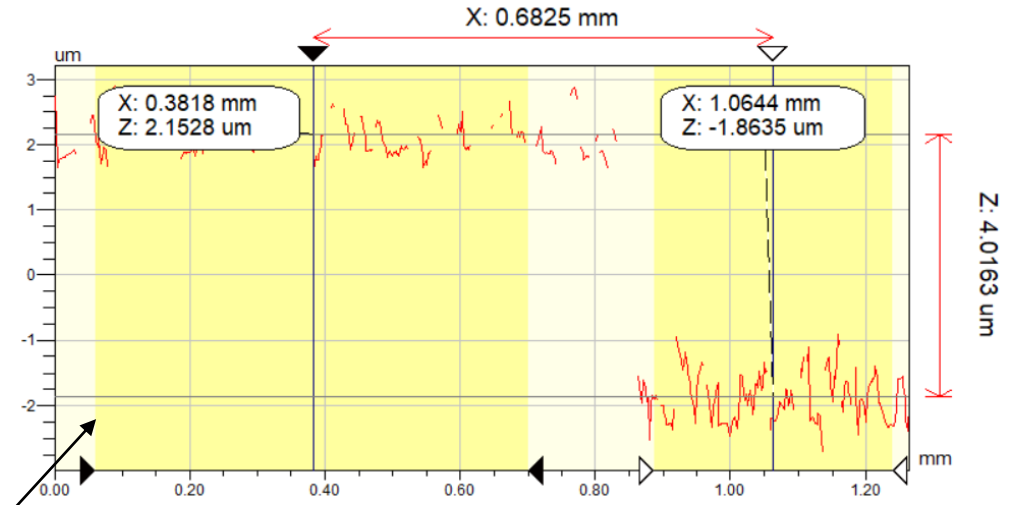
p- layer

p++ layer

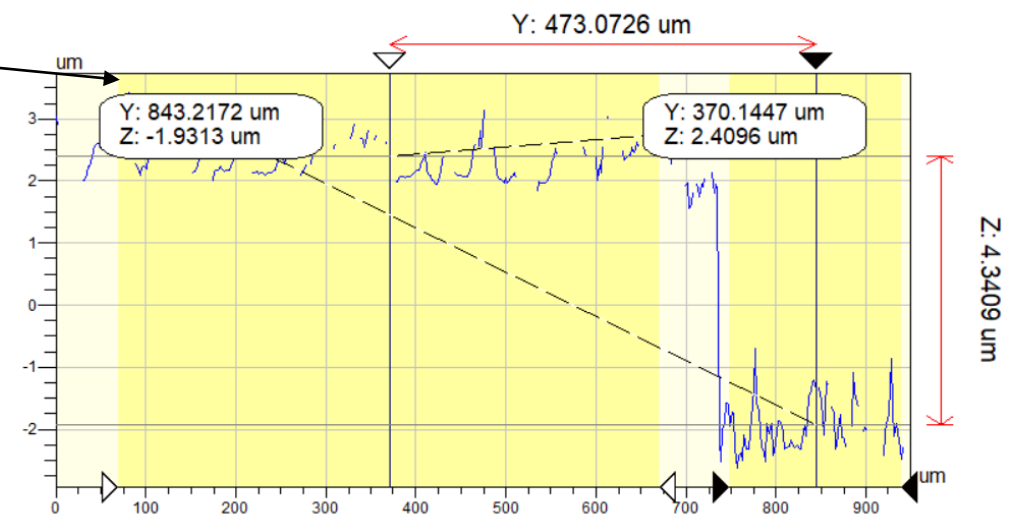
Optical profilometry of the sample



X Profile



Y Profile

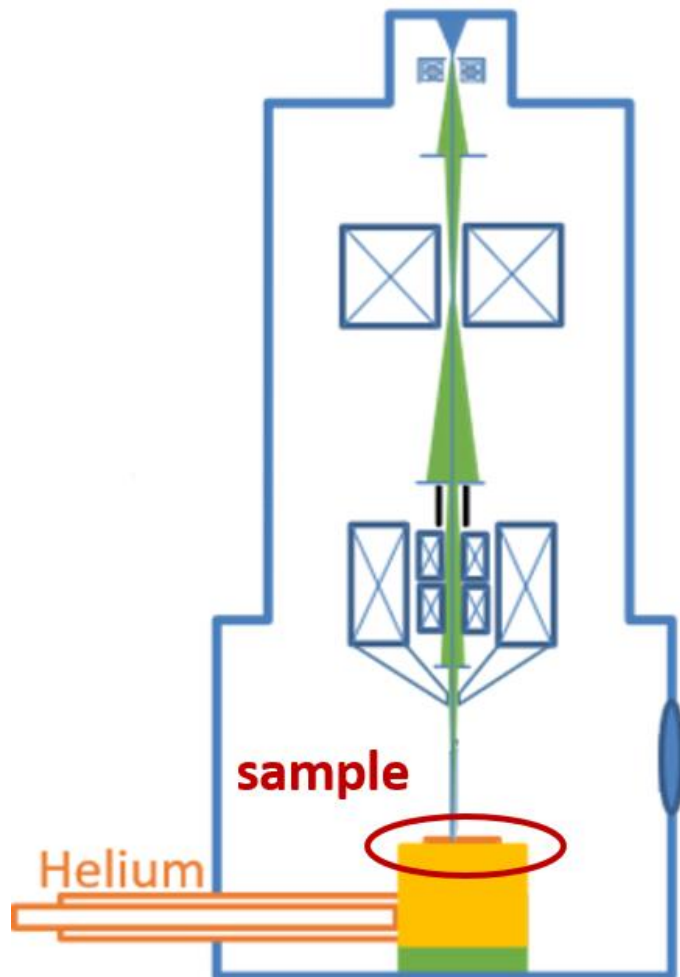


Outlines

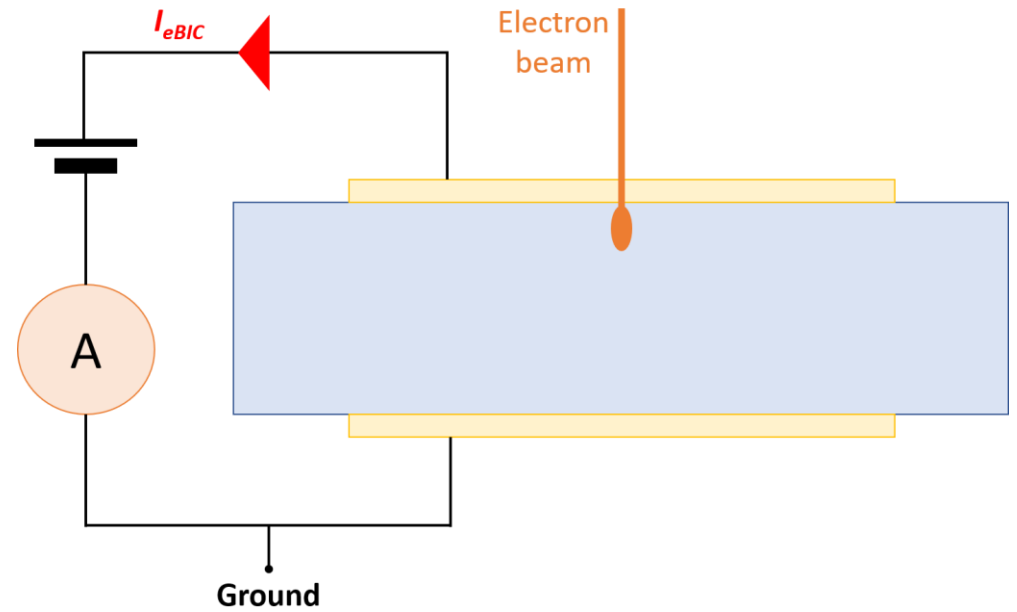
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eBIC setup

Scanning electron microscope (SEM) setup

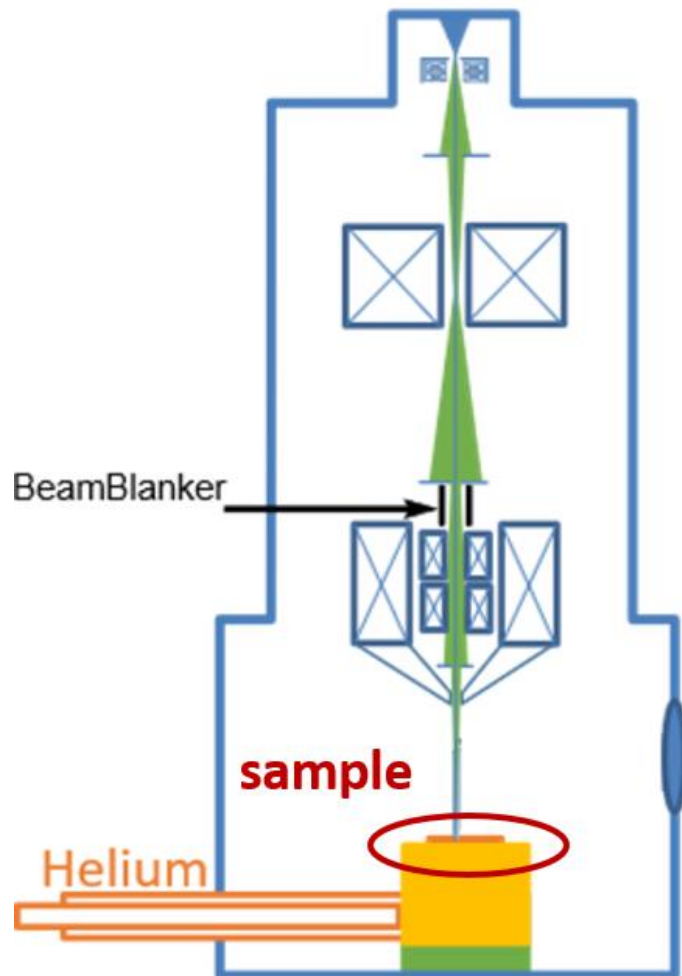


electron Beam Induced current (eBIC) setup

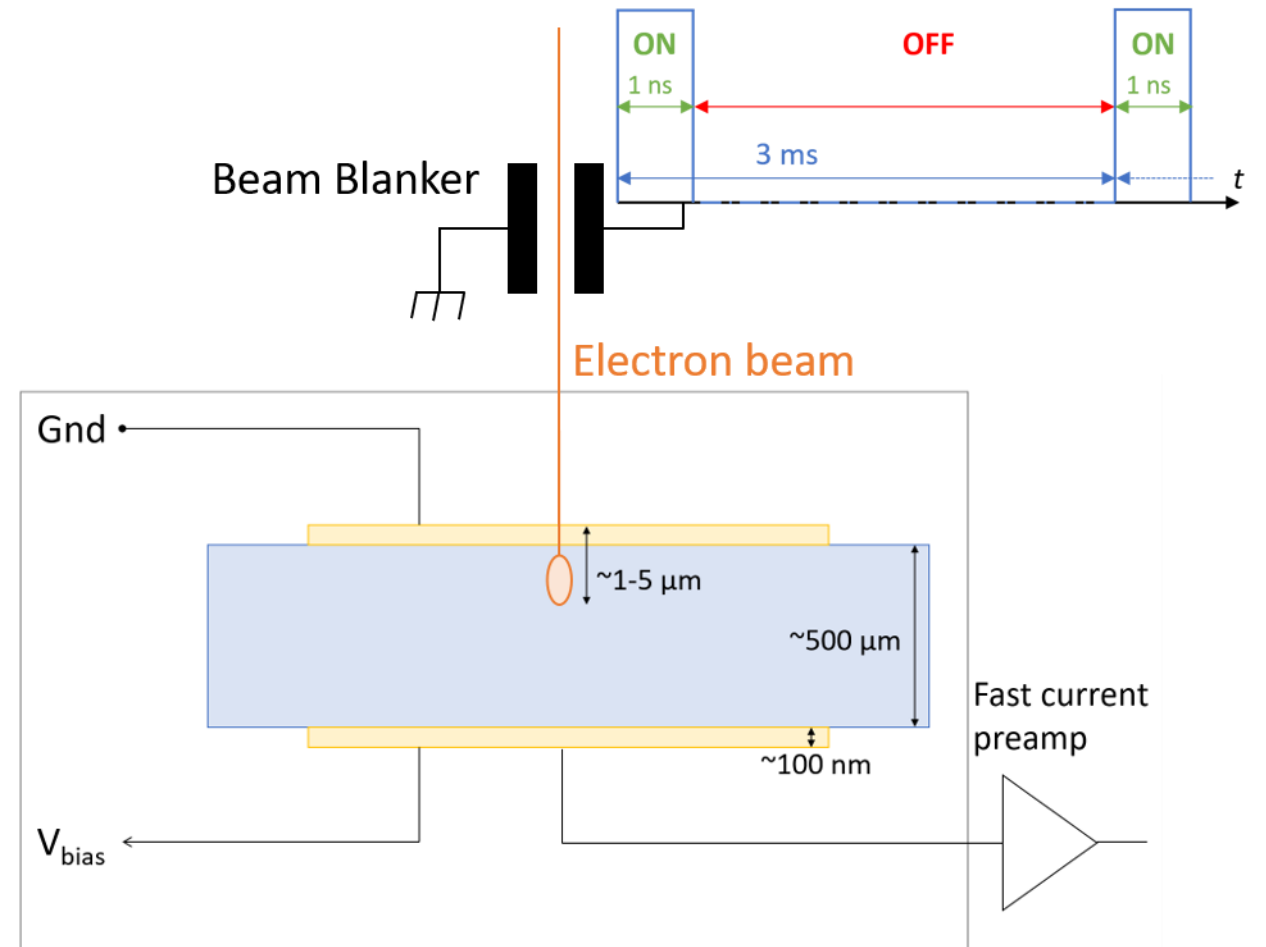


ToF – eBIC setup

Scanning electron microscope (SEM) setup

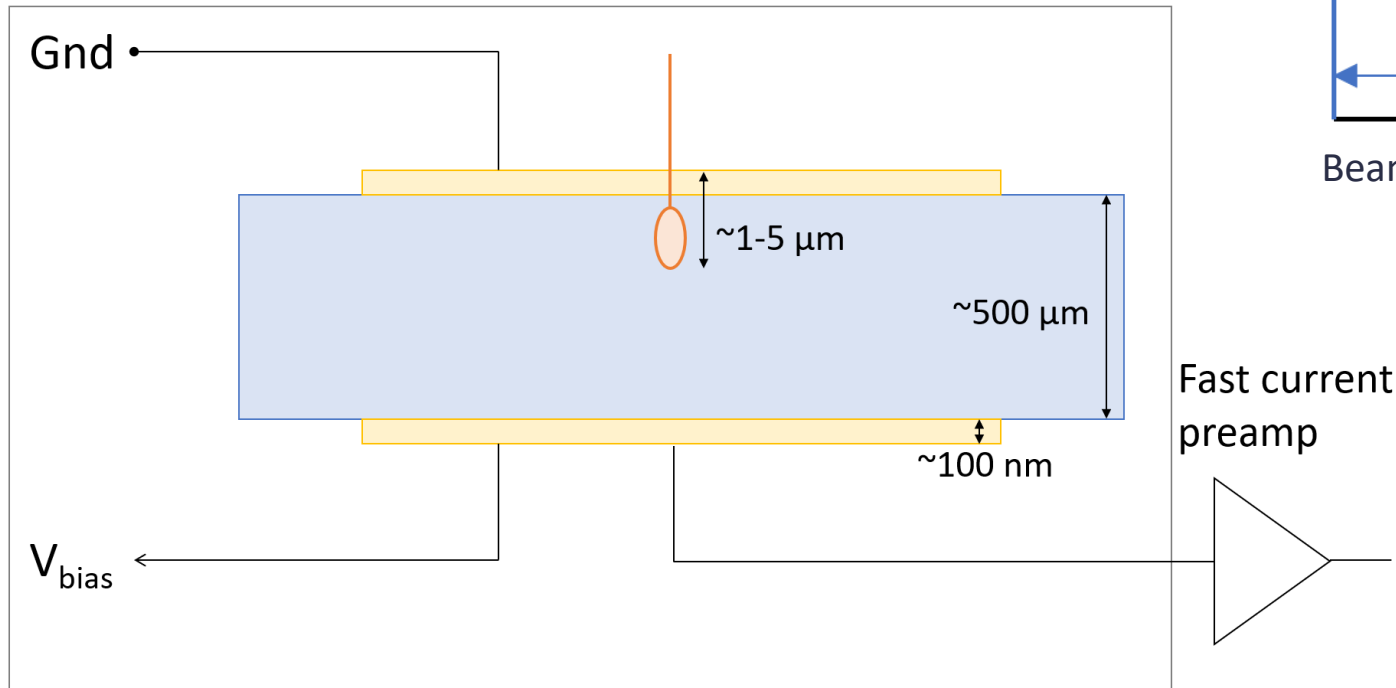


Time of Flight (ToF) – eBIC setup



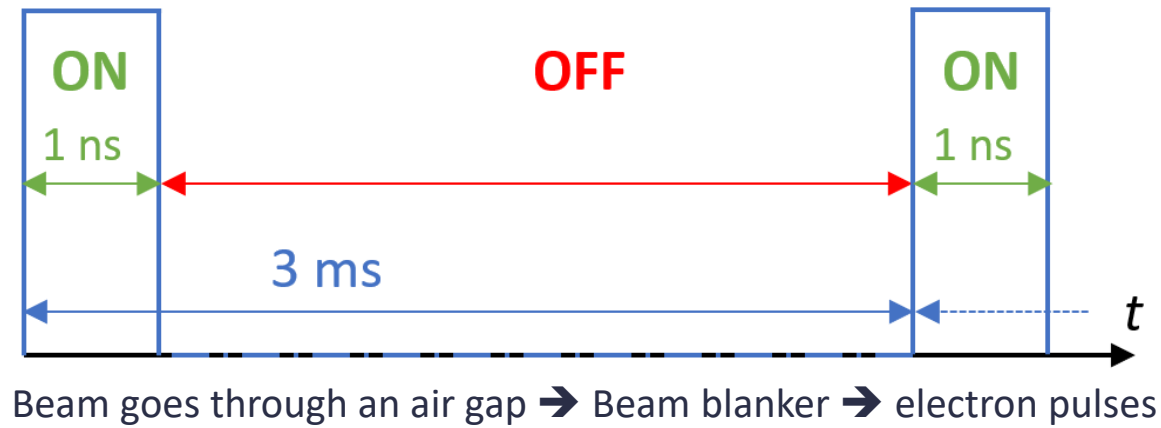
ToF – eBIC – goals and advantages

ToF – eBIC setup



Development of a ToF – eBIC setup with F. Donatini
(POM : Pôle Optique et Microscopie – Institut Néel)

ToF – eBIC : Time of Flight – electron Beam Induced Current



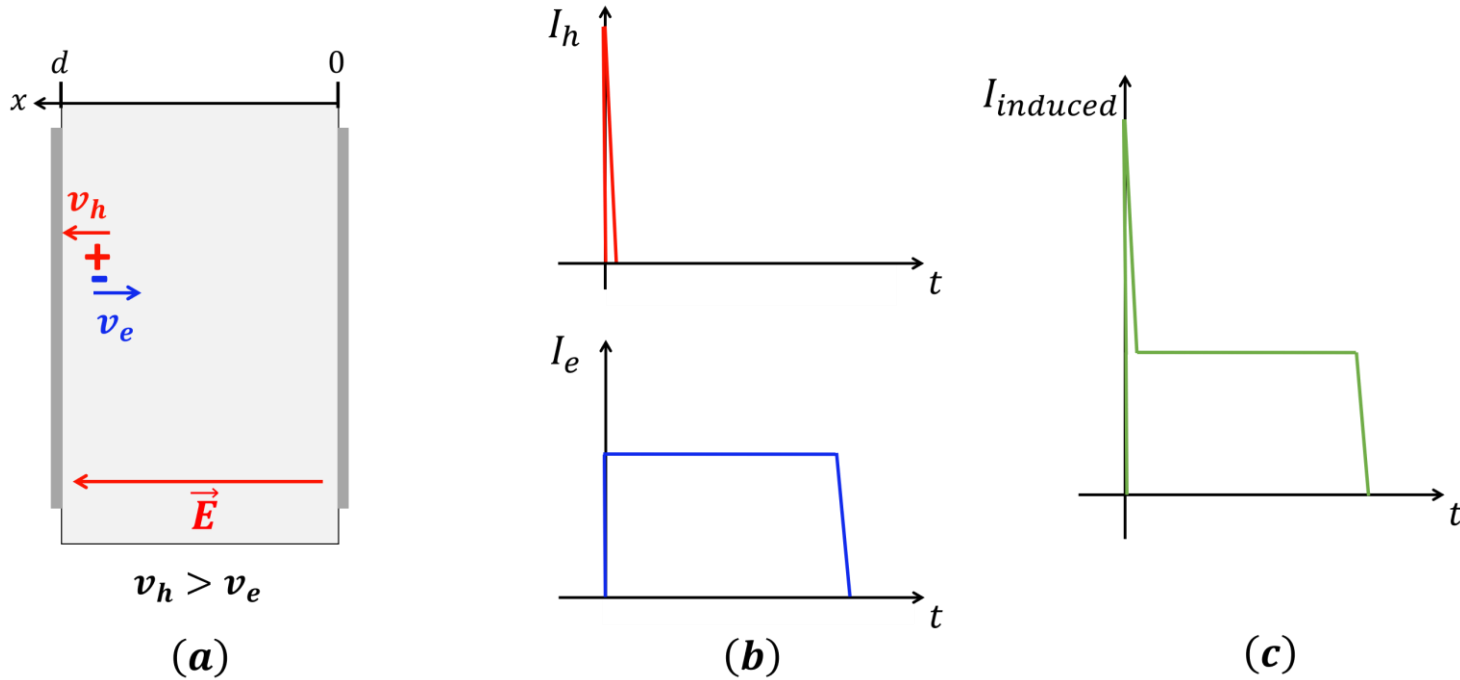
Goal: characterise the properties of the diamond using an electron beam (carrier mobilities)

Advantages:

- ✓ Setup **available** at Institut Néel
- ✓ Study one type of charge carrier (small penetration depth ($< 5 \mu\text{m}$))
- ✓ Electron \rightarrow do **not damaged** the detector
- ✓ Allow **beam monitoring** (energy, intensity...)
 - \rightarrow Possible to do a **2D mapping**
- ✓ Have an **external trigger**
- ✓ **Monitor the temperature**

Shockley-Ramo Theorem

Signal shape for low penetration rate particles (like alpha ions or electrons)



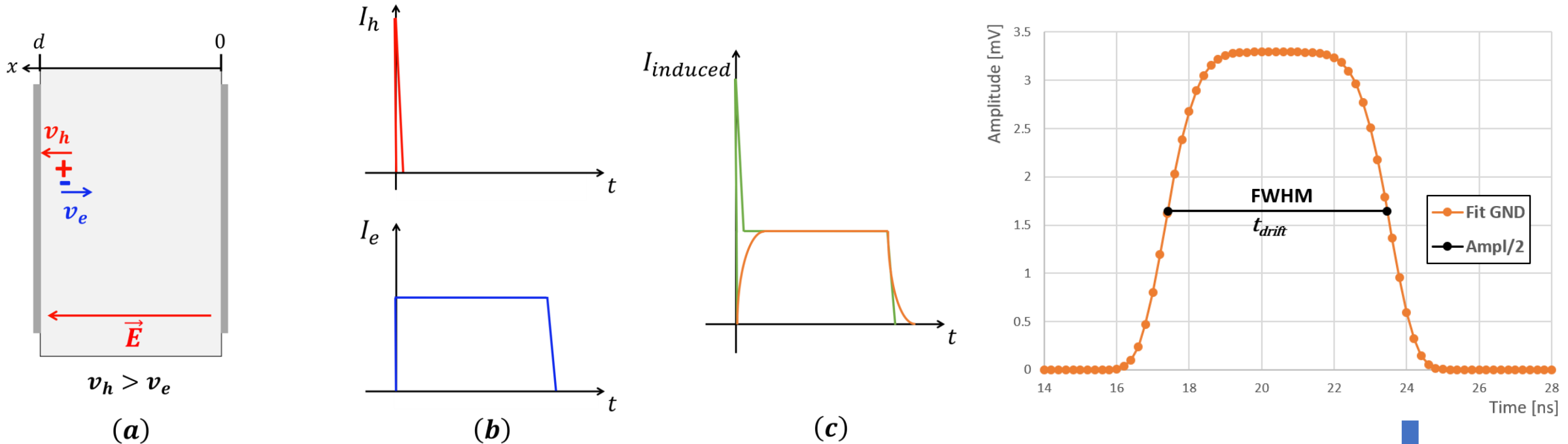
Shockley-Ramo theorem

$$I_{induced} = q \vec{v}_q \cdot \vec{E}_w$$

Charge movement induces a current on detector electrodes

Shockley-Ramo Theorem

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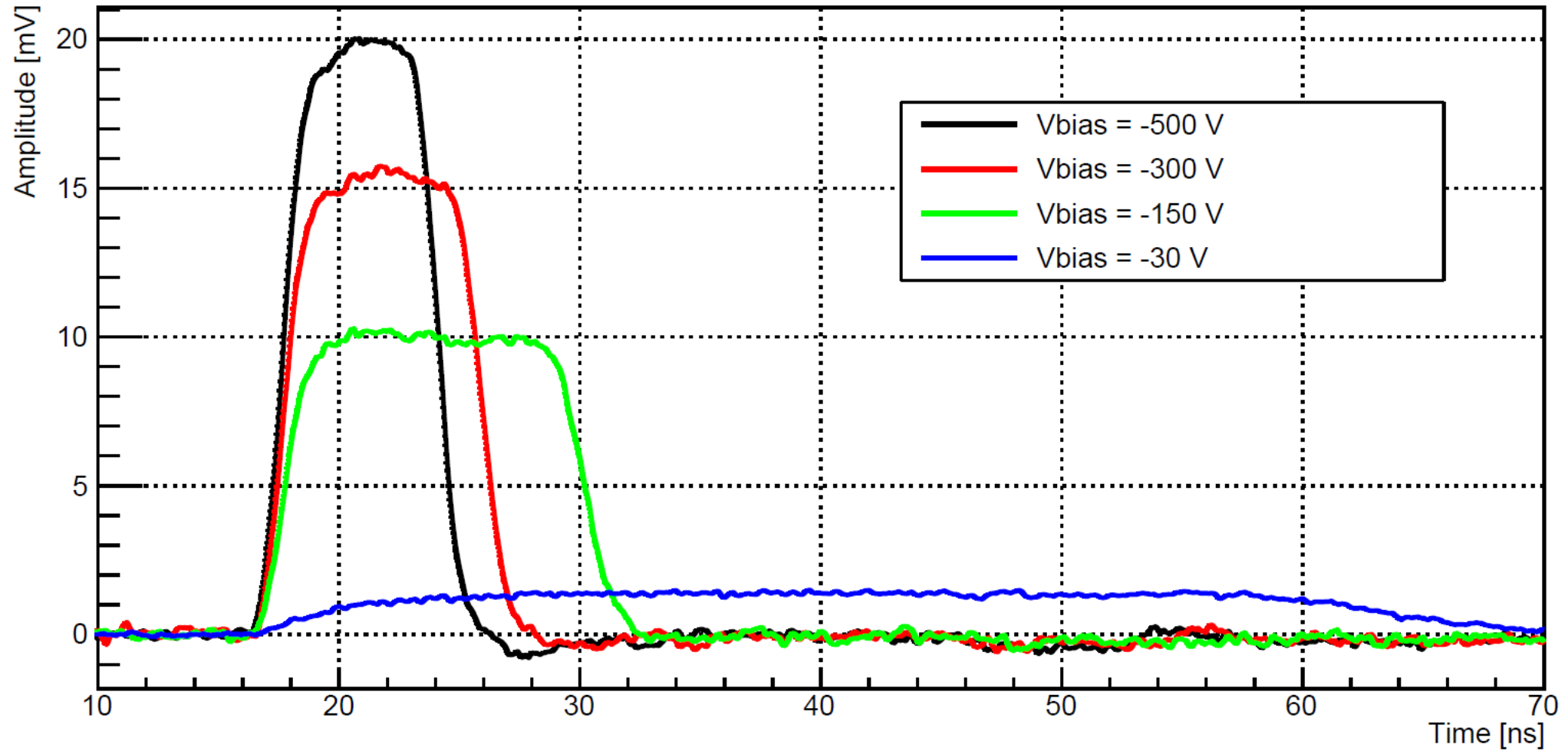
Charge movement induces a current on detector electrodes

Drift velocity calculation:

$$v_{drift} = \frac{d}{t_{drift}} = \frac{d}{FWHM}$$

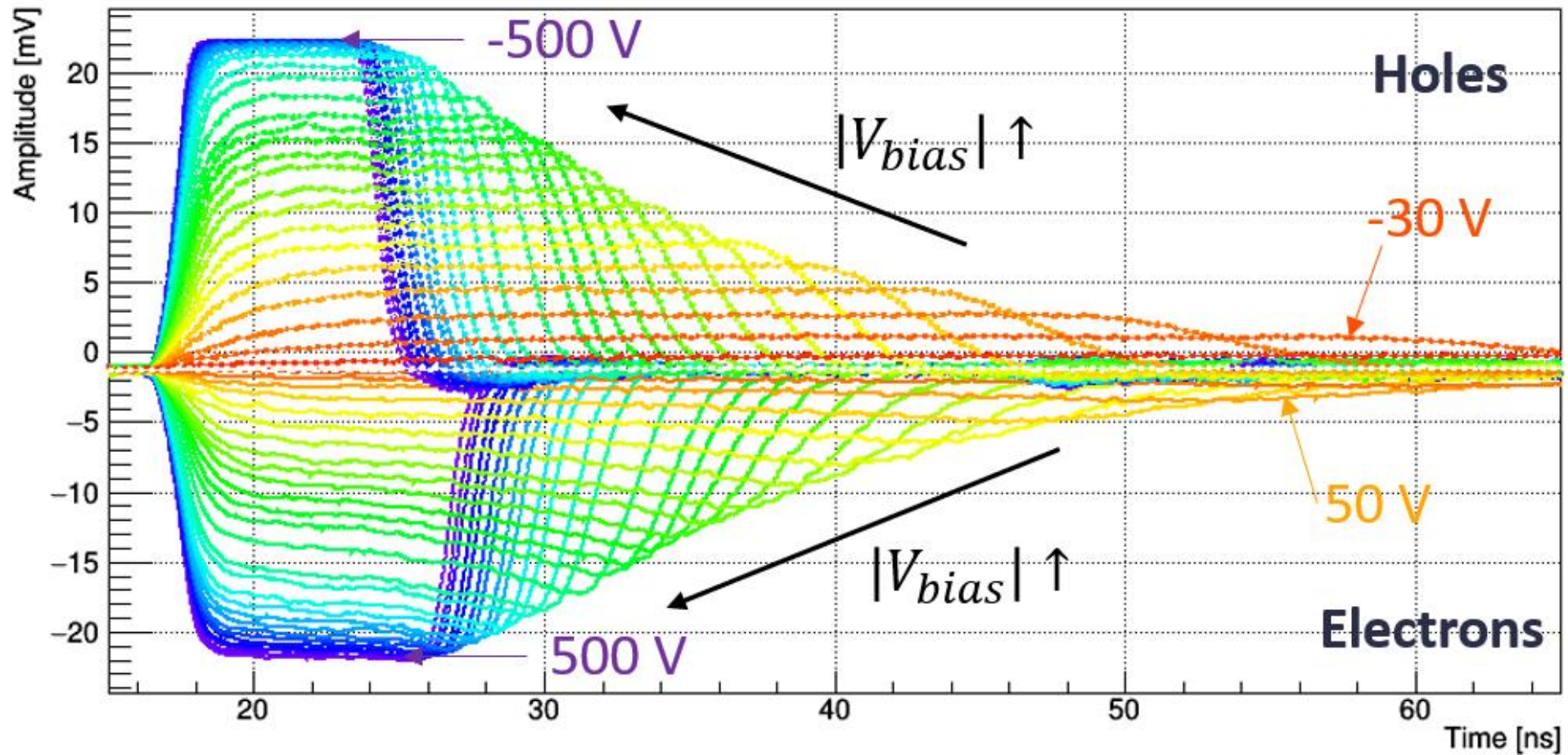
Traces for different polarizations

Signal observed on a scCVD diamond



Traces for different polarizations

Signal observed on a scCVD diamond



Drift velocity and mobility

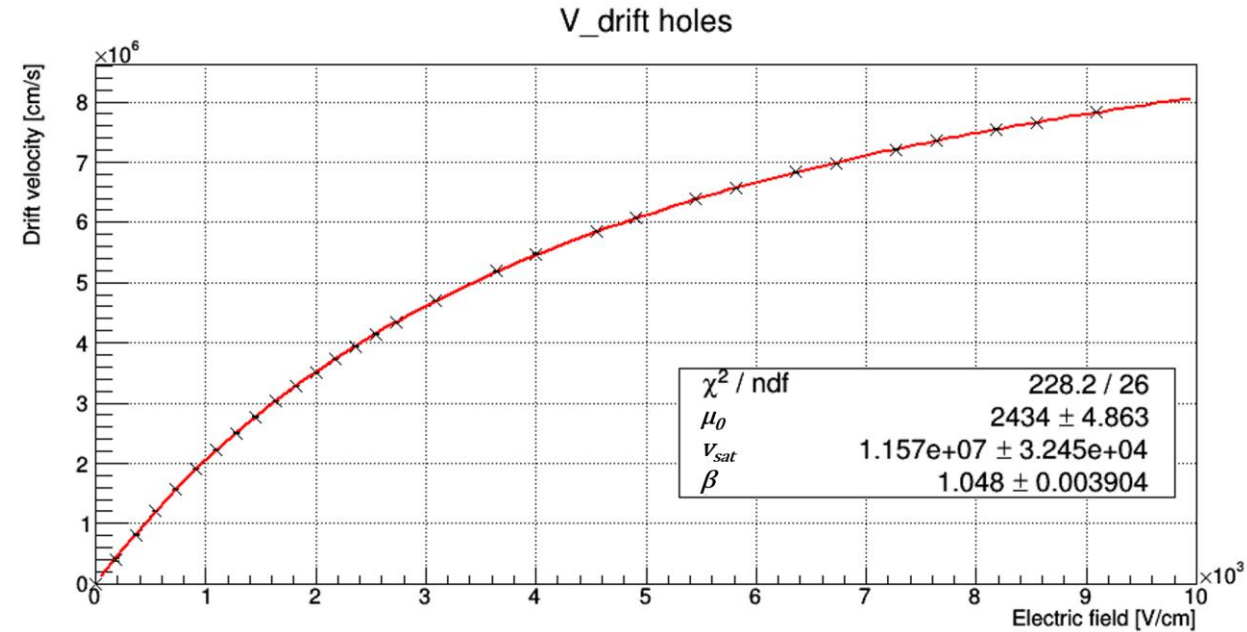
Signal observed on a scCVD diamond

Holes		
Measures	μ_0 [cm ² / (V.s)]	v_{sat} [10 ⁶ cm/s]
ToF – eBIC meas.	2334 ± 10	13.1 ± 0.1
LPSC α source meas.	2380 ± 20	12.1 ± 0.1
F. Marsolat *	2349 ± 28	14.1 ± 0.3

Electrons		
Measures	μ_0 [cm ² / (V.s)]	v_{sat} [10 ⁶ cm/s]
ToF – eBIC meas.	1853 ± 17	8.8 ± 0.1
LPSC α source meas.	2020 ± 20	8.2 ± 0.1
F. Marsolat *	2053 ± 87	9.2 ± 0.8

* F. marsolat, PhD Thesis, 2014 – measurement done with an α source

Drift velocity



Fit function:

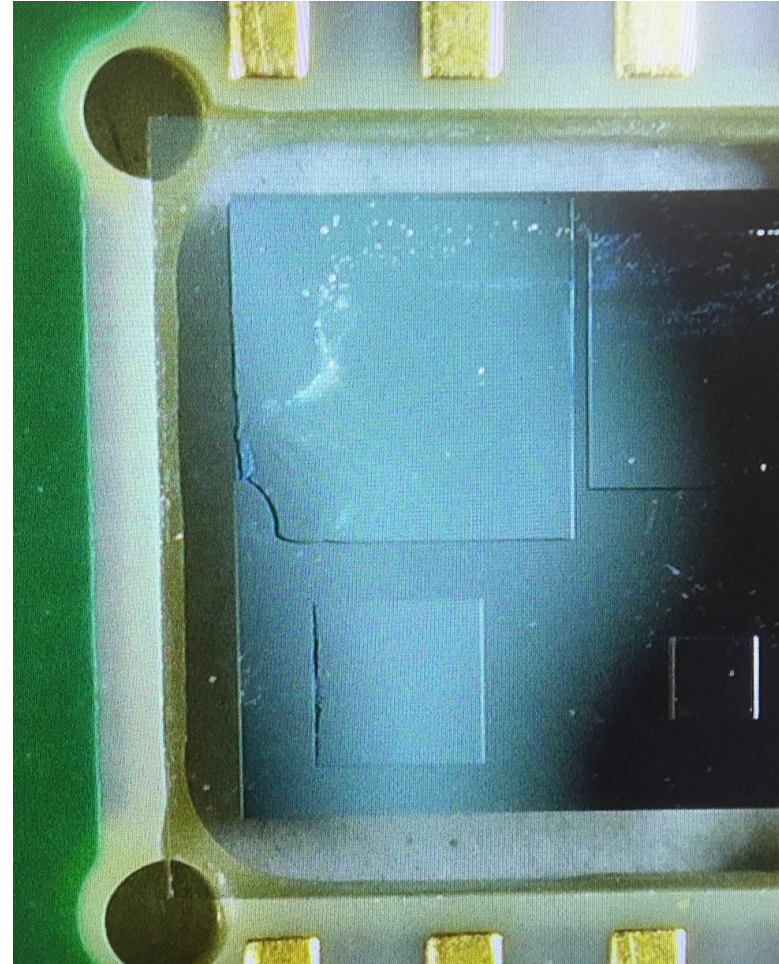
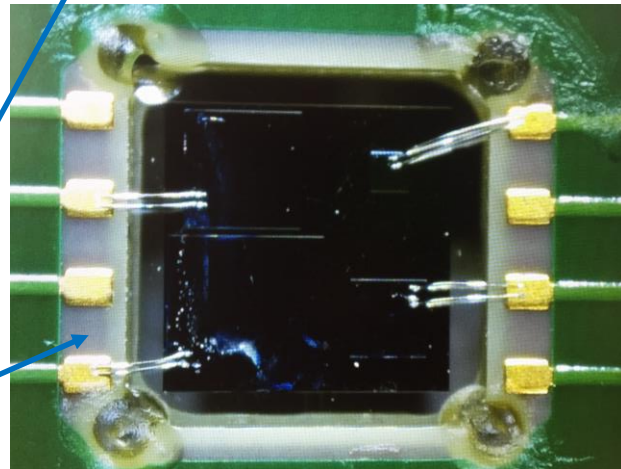
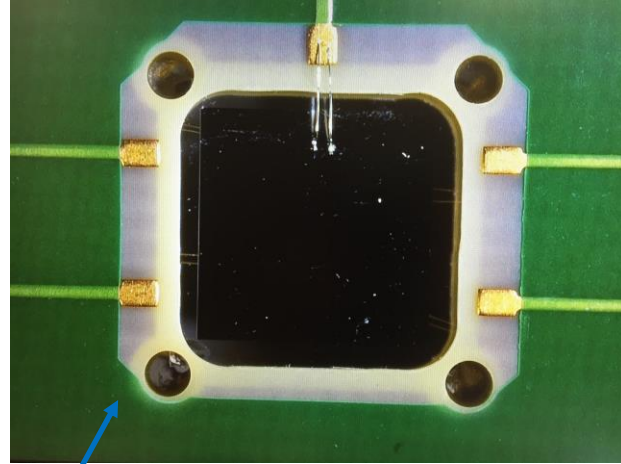
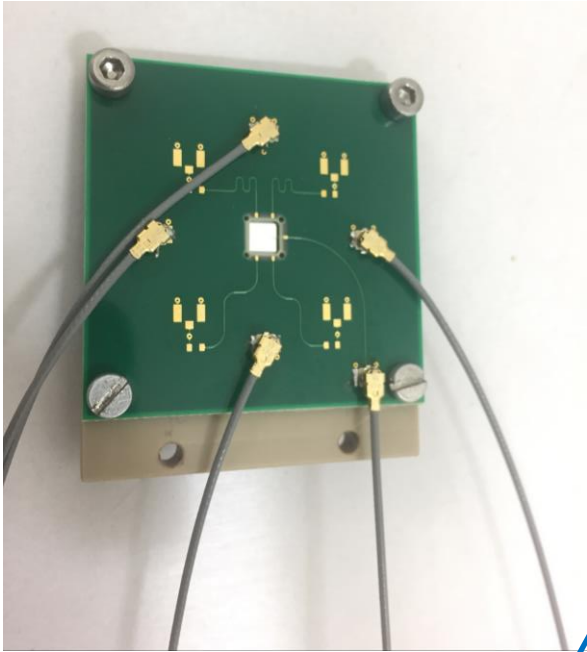
Caughy & Thomas, *Proc. IEE.* **33**,
p. 1765-1766 (1965)

$$v_{drift}(E) = \frac{\mu_0 E}{\left[1 + \left(\frac{\mu_0 E}{v_{sat}} \right)^\beta \right]^{1/\beta}}$$

μ_0 Low field mobility
 v_{sat} Saturation drift velocity

Mapping of the detector response

Picture of a pixelated diamond

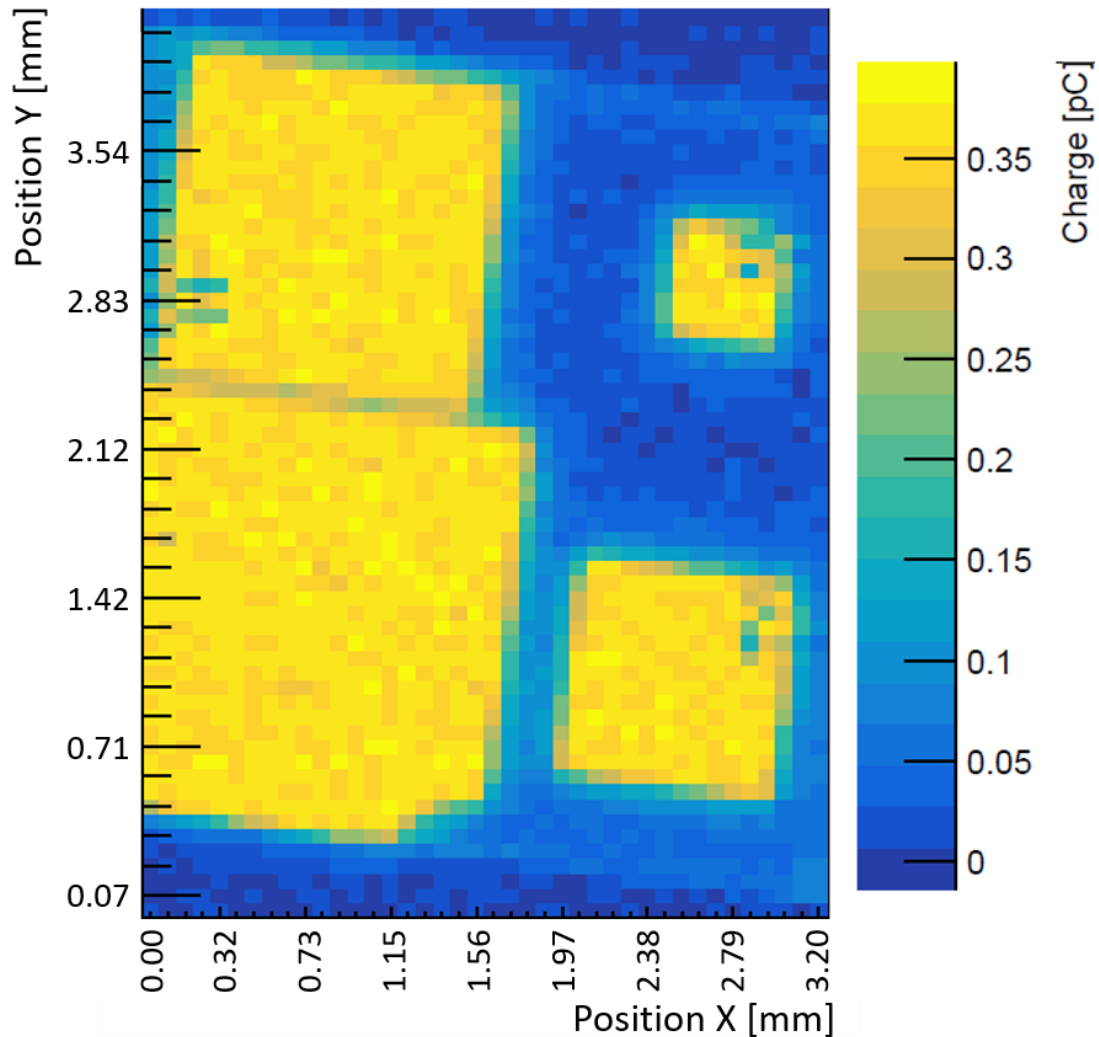


Metallization different on the two faces:

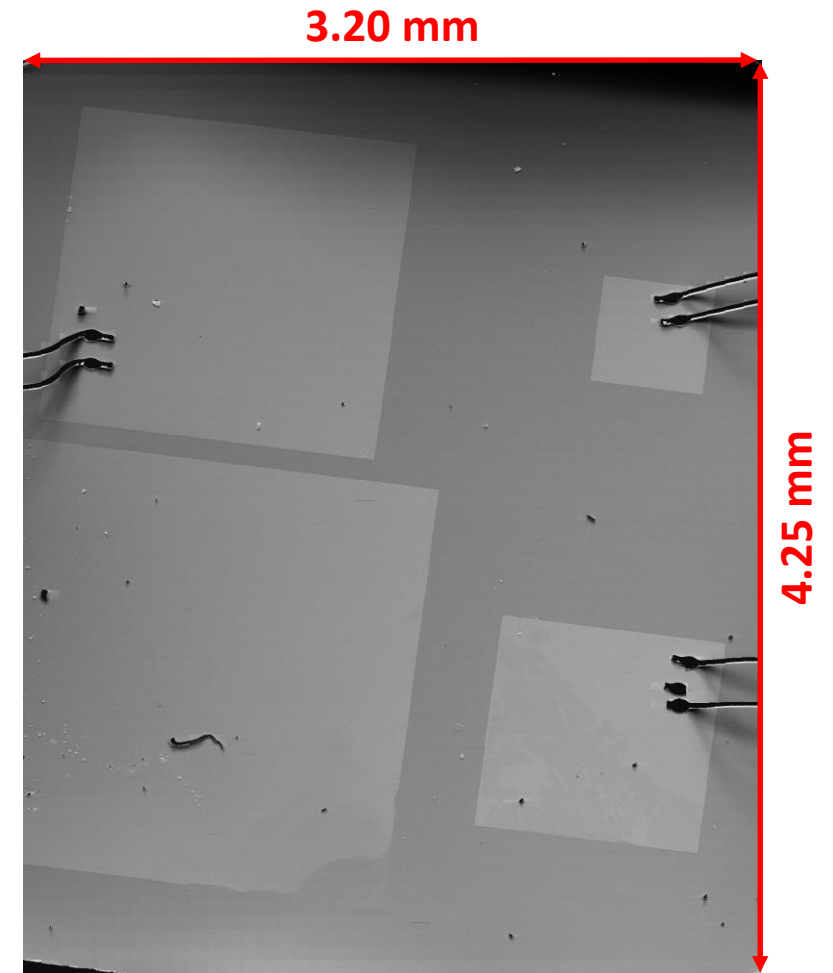
- Fully metallized face
- Pixelated face

Mapping of the detector response

Coarse mapping of detector charge response



SEM mapping picture



Conclusions and perspectives

Work done ΔE -E detector

- SRIM simulations done → **1st detector design based on light ions (⁴He)**
- Manufacture of the 1st sample : work in progress

ToF – eBIC experiments:

- **First ToF – eBIC setup**
- Beam parameters optimization: work in progress
- Study the transport properties of charge carriers at different temperatures
- Charge mapping of the detector

Perspectives ΔE -E detector

- p- stage tests of the 1st sample
- Manufacture of the 2nd sample + detector tests (LPSC setup, AIFIRA, eBIC...)
- Fission Fragment (FF) adapted design
- Experiments à ILL

ToF – eBIC experiments:

- **2 conferences (orals) 2021 MRS Spring Meeting** (April) and **NDNC** (June) and **write an article**
- Make the test bench technologically accessible (write technological instructions) → experimental platform open to other experiments in diamond international community



Thank you for your attention!

